

Attorney Docket No. 5649-1215

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: SoonHo Kim et al;

Application No.: not yet assigned

Filed: concurrently herewith

For: PHOTOMASKS INCLUDING SHADOWING ELEMENTS THEREIN AND
RELATED METHODS AND SYSTEMS

Date: February 9, 2004

MAIL STOP PATENT APPLICATION

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)

Sir:

Attached is a list of documents on Form PTO-1449, together with a copy of any listed foreign patent document and/or non-patent literature. A copy of any listed U.S. patent and/or U.S. patent application publication is not provided herewith in accordance with the waiver by the U.S. Patent and Trademark Office of requirements under 37 C.F.R. § 1.98(a)(2)(i) for all U.S. national patent applications filed after June 30, 2003 and for all international applications that have entered the national stage under 35 USC § 371 after June 30, 2003.

It is requested that these documents be considered by the Examiner and officially made of record in accordance with the provisions of 37 C.F.R. § 1.56 and Section 609 of the MPEP.

No fee is believed due. However, the Commissioner is hereby authorized to charge any deficiency or credit any overpayment to Deposit Account No. 50-0220.

Respectfully submitted,


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Joyce Paoli

Substitute form 1449A/PTO			Complete if Known		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)			Application Number	not yet assigned	
			Filing Date	concurrently herewith	
			First Named Inventor	SooHo Kim	
			Group Art Unit	not yet assigned	
			Examiner Name	not yet assigned	
Sheet	1	of	1	Attorney Docket Number	5649-1215

U.S. PATENTS AND PATENT PUBLICATIONS					
Examiner Initials*	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
		Number	Kind Code (if known)		
	1.	US-2001-0012099		Kumagai	08/09/2001
	2.	US-2001-0019407		Sato et al;	09/06/2001
	3.	US-4,861,402		Gordon	08/29/1989
	4.	US-5,745,617		Starodubov et al;	04/28/1998
	5.	US-6,335,126		Kondou et al;	01/01/2001
	6.	US-6,544,914		Kikugawa et al;	04/08/2003
	7.	US-10/623,616			
		US-			
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		US-			
		US-			

FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	T
		Office	Number	Kind Code (if known)			
	8.		1999-0065144		Korean	08/05/1999	
	9.		2001-0052399		Korean	06/25/2001	
	10.		2001-0062343		Korean	07/07/2001	
	11.		2002-0027803		Korean	04/15/2002	
	12.		2003-0029329		Korean	04/14/2003	
	13.		9-61986		Japanese	03/07/1997	
	14.		2001-272764		Japanese	10/05/2001	

OTHER NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T
	15.	N.H. Rizvi; "Femtosecond laser micromachining: Current status and applications, RIKEN Review No. 50 Focused on Laser Precision Microfabrication (LPM 2002), January 2003 pp 1-9	
	16.	"Photomask Defect Repair Systems" DRS Series; Industrial - Photomask Defect Repair Systems, Quantronix Products Catalog 2003, pp 24-60.	

Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.